

EAST Search History

EAST Search History (Prior Art)

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	29	US-5526293-\$.D.ID. OR US-5583780-\$.D.ID. OR US-5866437-\$.D.ID. OR US-6304834-\$.D.ID. OR US-20020107604-\$.D.ID. OR US-20030078738-\$.D.ID. OR US-20030101251-\$.D.ID. OR US-6571371-\$.D.ID. OR US-6560503-\$.D.ID. OR US-20030135302-\$.D.ID. OR US-6587744-\$.D.ID. OR US-6628809-\$.D.ID. OR US-6643616-\$.D.ID. OR US-20040078319-\$.D.ID. OR US-6728591-\$.D.ID. OR US-20040102934-\$.D.ID. OR US-6757645-\$.D.ID. OR US-6763277-\$.D.ID. OR US-6774998-\$.D.ID. OR US-6810296-\$.D.ID. OR US-6812045-\$.D.ID. OR US-20050010319-\$.D.ID. OR US-20050016947-\$.D.ID. OR US-6905895-\$.D.ID. OR US-7055112-\$.D.ID. OR US-7184850-\$.D.ID. OR US-7333871-\$.D.ID. OR US-7356377-\$.D.ID. OR US-7622308-\$.D.ID.	US-PGPUB; USPAT	OR	OFF	2011/07/26 11:36
S140	15	(semiconductor near3 (process\$4 too154 equipment manufactur\$4)) with ((model\$4 simulat\$4) with ((physical geometry) near2 (machine tool manufactur\$4 assembly)))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2011/07/25 12:23
S139	0	(semiconductor near3 (process\$4 too154 equipment manufactur\$4)) and ((model\$4 simulat\$4) with ((physical geometry) near2 (machine tool manufactur\$4 assembly))) and (("re" adj (using use)) with (known start\$4 precomputed stor\$4) with (result solution output))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2011/07/25 12:22
S138	0	(semiconductor near3 (process\$4 too154 equipment manufactur\$4)) and ((model\$4 simulat\$4) with ((physical geometry) near2 (machine tool manufactur\$4 assembly))) and (("re" adj (using use)) with (known start\$4 precomputed stor\$4) with (result solution output))	US-PGPUB; USPAT	OR	OFF	2011/07/25 12:22
S137	79	(semiconductor near3 (process\$4 too154 equipment manufactur\$4)) and ((model\$4 simulat\$4) with((physical geometry) near2 (machine tool manufactur\$4 assembly))) and ((parallel near3 process\$4) (code adj parallel\$8) ((plural distributed multiple) near4 simulat\$4) and grid)	US-PGPUB; USPAT	OR	OFF	2011/07/25 12:18
S136	1431	703/22.ccls.	US-PGPUB; USPAT	OR	OFF	2011/07/25 12:17

S135	899	700/95.ccls.	US-PGPUB; USPAT	OR	OFF	2011/07/25 12:17
S134	0	700/95.ccls. and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (grid mesh element))	US-PGPUB; USPAT	OR	OFF	2011/07/25 12:16
S133	8	"438"/\$.ccls. and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (distribut\$4 with (model\$4 simulat\$4 execut\$4)))	US-PGPUB; USPAT	OR	OFF	2011/07/25 12:15
S132	1	700/29-31.ccls. and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (distribut\$4 with (model\$4 simulat\$4 execut\$4)))	US-PGPUB; USPAT	OR	OFF	2011/07/25 12:14
S131	2	700/29-31.ccls. and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (grid mesh element))	US-PGPUB; USPAT	OR	OFF	2011/07/25 12:14
S130	9	(S109 S110 S111 S120) and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (grid cell geometr\$4 (physical adj geometr\$4))).clm.	US-PGPUB; USPAT	OR	OFF	2011/07/25 12:11
S129	162	(ERI C near2 STRANG).inv. OR (ANDREJ near2 MITROVIC).inv.	US-PGPUB; USPAT	OR	OFF	2011/07/25 12:06
S128	627	(STRANG).inv. OR (MITROVIC).inv.	US-PGPUB; USPAT	OR	OFF	2011/07/25 12:05
S127	0	(S109 S110 S111 S120) and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (((re adj use) lookup) with result solution)).clm.	US-PGPUB; USPAT	OR	OFF	2011/07/25 12:04
S125	8	(S120) and ((model\$4 simulat\$4) with (grid mesh\$4 element) with (semiconductor near2 (tool assembly manufactur\$4 equipment)))	US-PGPUB; USPAT	OR	OFF	2011/07/25 12:02
S124	156	(S120) and ((model\$4 simulat\$4) with (grid mesh\$4 element))	US-PGPUB; USPAT	OR	OFF	2011/07/25 12:01
S123	0	S120 and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (((re adj use)lookup) with result solution)).clm.	US-PGPUB; USPAT	OR	OFF	2011/07/25 12:01
S122	55	S120 and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment))).clm.	US-PGPUB; USPAT	OR	OFF	2011/07/25 12:00
S121	0	S120 and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (distributed adj simulat\$4)).clm.	US-PGPUB; USPAT	OR	OFF	2011/07/25 12:00
S120	2858	700/121.ccls.	US-PGPUB; USPAT	OR	OFF	2011/07/25 11:59
S119	118	(S109 S110 S111) and ((model\$4 simulat\$4) with (grid mesh\$4 element) with (geometr\$4))	US-PGPUB; USPAT	OR	OFF	2011/07/25 11:59
S118	916	(S109 S110 S111) and ((model\$4 simulat\$4) with (grid mesh\$4 element))	US-PGPUB; USPAT	OR	OFF	2011/07/25 11:58

S117	0	((S109 OR S110) and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (distributed adj simulat\$4)).clm.	US-PGPUB; USPAT	OR	OFF	2011/07/25 11:57
S116	0	S110 and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (((re adj use)lookup) with result solution)).clm.	US-PGPUB; USPAT	OR	OFF	2011/07/25 11:57
S115	0	S109 and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (((re adj use)lookup) with result solution)).clm.	US-PGPUB; USPAT	OR	OFF	2011/07/25 11:57
S114	0	S111 and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (((re adj use)lookup) with result solution)).clm.	US-PGPUB; USPAT	OR	OFF	2011/07/25 11:57
S113	4	S111 and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment))).clm.	US-PGPUB; USPAT	OR	OFF	2011/07/25 11:56
S112	0	S111 and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (distributed adj simulat\$4)).clm.	US-PGPUB; USPAT	OR	OFF	2011/07/25 11:55
S111	809	438/5.ccls.	US-PGPUB; USPAT	OR	OFF	2011/07/25 11:54
S110	936	703/7.ccls.	US-PGPUB; USPAT	OR	OFF	2011/07/25 11:54
S109	2069	703/13.ccls.	US-PGPUB; USPAT	OR	OFF	2011/07/25 11:54
S108	1441	703/13.ccls.	USPAT	OR	OFF	2011/07/25 11:54

EAST Search History (Interference)

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S147	0	700/121.ccls. and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (((re adj use)lookup) with result solution)).clm.	USPAT; UPAD	OR	OFF	2011/07/25 12:27
S146	0	703/7,13,22.ccls. and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (((re adj use)lookup) with result solution)).clm.	USPAT; UPAD	OR	OFF	2011/07/25 12:27
S145	0	703/7,13,22.ccls. and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (((re adj use)lookup) with result solution)).clm.	USPAT; UPAD	OR	OFF	2011/07/25 12:27
S144	0	703/7,13,22.ccls. and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (((re adj use)lookup) with result solution)).clm.	USPAT; UPAD	OR	OFF	2011/07/25 12:26
S143	0	438/5.ccls. and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (((re adj use)lookup) with result solution)).clm.	USPAT; UPAD	OR	OFF	2011/07/25 12:26
S142	0	438/5.ccls. and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly	USPAT; UPAD	OR	OFF	2011/07/25 12:26

		manufactur\$4 equipment)) with (((re adj use lookup) with result solution)).dm.				
S141	0	438/5.cds. and ((model\$4 simulat\$4) with (semiconductor near2 (tool assembly manufactur\$4 equipment)) with (distributed adj simulat\$4)).clm.	USPAT; UPAD	OR	OFF	2011/07/25 12:25

7/26/2011 11:50:15 AM

C:\Users\asaxena\Documents\EAST\Workspaces\10673507_updated.wsp